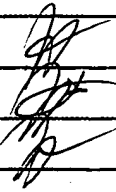
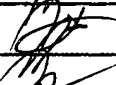
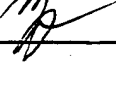


| | | | |
|--|--|--|---------------------------|
| FORM PTO-1449 | U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE | ATTORNEY DOCKET NUMBER 024808-00014 | NEW PATENT APPLICATION |
| LIST OF REFERENCES CITED BY APPLICANT (Use several sheets if necessary) | | APPLICANT Kazunari HONMA, et al. | |
| | | FILING DATE August 1, 2003 | GROUP |

U.S. PATENT DOCUMENTS

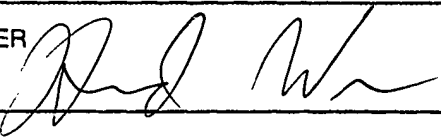
| EXAMINER INITIAL | | DOCUMENT NUMBER | DATE | NAME | CLASS | SUB- CLASS | FILING DATE |
|---------------------|----|--------------------|------|------|-------|---------------|----------------|
| | AA | | | | | | |
| | AB | | | | | | |
| | AC | | | | | | |
| | AD | | | | | | |
| | AE | | | | | | |
| | AF | | | | | | |

FOREIGN PATENT DOCUMENTS

| | | DOCUMENT NUMBER | DATE | COUNTRY | CLASS | SUB- CLASS | TRANSLATION YES NO PART. | | |
|---|----|--------------------|----------------|---------|-------|---------------|-----------------------------|--|---|
|  | AG | 11-068057 | March 9, 1999 | Japan | | | | | X |
|  | AH | 2001-072416 | March 21, 2001 | Japan | | | | | X |
|  | AI | 11-080181 | March 26, 1999 | Japan | | | | | X |
| | AJ | | | | | | | | |
| | AK | | | | | | | | |
| | AL | | | | | | | | |

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

| | | |
|--|----|--|
| | AM | Item I "Low Temperature Deposition Material" Section 4 "New Deposition Material" Ferroelectric Memory Advanced Process September 13, 1999 |
| | AN | |
| | AO | |

| | |
|---|----------------------------|
| EXAMINER  | DATE CONSIDERED 11/4/05 |
| *EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. | |